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FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. IMEC197.001CP1	APPLICATION NO. 10/670,754
	APPLICANT Solanki, Chetan Singh	
	FILING DATE September 24, 2003	GROUP 3661 2829

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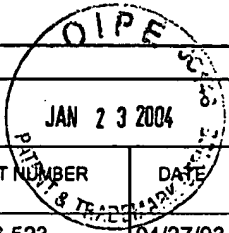
U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
SP	1	5,206,523	04/27/93	Goesele, et al.	—	—	
SP	2	6,326,280 B1	12/04/01	Tayanaka	—	—	
SP	3	6,331,208 B1	12/18/01	Nishida, et al.	—	—	
SP	4	6,350,702 B2	02/26/02	Sakaguchi, et al.	—	—	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO
ε	5	EP 0 226 091 A2	06/24/87	EUROPE	—	—	X	
ε	6	EP 0 797 258 A2	09/24/97	EUROPE	—	—	X	
ε	7	EP 0 975 012 A2	01/26/00	EUROPE	—	—	X	

EXAMINER INITIAL		OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
ε	8	Bender, et al., "Morphological properties of porous-Si layers for n^+-emitter applications", Applied Surface Science, Vol. 47, pp. 187-200), (1999).
ε	9	Billat, et al., "Influence of etch stops on the microstructure of porous silicon layers", Thin Solid Films, Vol. 297, pp. 22-25, (1997).
ε	10	Ookubo, et al., "Microscope observation of a self-standing film of porous silicon", Materials Science and Engineering, Vol. B20, pp. 324-327, (1993).
ε	11	Rinke, et al., "Quasi-monocrystalline silicon for thin-film devices", Applied Physics A, 68, pp. 705-707, (1999).
ε	12	Tayanaka, et al., "Thin-film crystalline silicon solar cells obtained by separation of a porous silicon sacrificial layer", 2nd Wold Conference and Exhibition on Photovoltaic Solar Energy Conversion, Vienna, Austria, 1272 (July 6-10, 1998).
ε	13	European Search Reports for European Application No. EP 00 87 0040, dated August 28, 2000.

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EXAMINER Evan Pert	DATE CONSIDERED 10/5/04

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